

Title (en)

Method and apparatus for dressing polishing cloth

Title (de)

Verfahren und Vorrichtung zum Abrichten von Poliertuch

Title (fr)

Procédé et dispositif pour dresser un tissu de polissage

Publication

EP 0769350 A1 19970423 (EN)

Application

EP 96116818 A 19961018

Priority

- JP 29610795 A 19951019
- JP 29610895 A 19951019

Abstract (en)

A polishing cloth mounted on a turntable is dressed by a dresser for restoring polishing capability of the polishing cloth. The dresser comprises a dresser body and an annular diamond grain layer provided on the dresser body, and the annular diamond grain layer is made of diamond grains which are electrodeposited. Alternatively, the dresser comprises a dresser body and a SiC layer provided on the dresser body. The dressing of the polishing cloth is performed by bringing the diamond grain layer or the SiC layer into contact with the polishing cloth while the turntable and the dresser are rotating. <IMAGE>

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B24B 53/00; B24B 37/04

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B24B 37/04 (2012.01)

CPC (source: EP KR)

B24B 37/042 (2013.01 - EP); **B24B 53/017** (2013.01 - EP); **H01L 21/304** (2013.01 - KR)

Citation (search report)

- [A] GB 2287422 A 19950920 - NEC CORP [JP]
- [PA] US 5486131 A 19960123 - CESNA JOSEPH V [US], et al
- [PA] US 5531635 A 19960702 - MOGI KATSUMI [JP], et al
- [A] PATENT ABSTRACTS OF JAPAN vol. 012, no. 292 (M - 729) 10 August 1988 (1988-08-10)

Cited by

EP1197296A3; US6899612B2; US9802293B1; WO9911431A1; WO2004077520A3; TWI728188B

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